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External Appendix E
for EHS-00072 SPEC FOR LIFT STATIONS

**SEMICONDUCTOR MANUFACTURING TECHNOLOGY
(SEMATECH)
ANNUAL INSPECTION SHEET**

REVISION

Rev No.	DCN No.	Change Summary	Release Date	DCN Initiator	Document Owner
1	DCN1000	Initial Release	11-13-13	K. Brust	R. Segura

Prior revision history, if applicable, is available from the Document Control Office.

1 PURPOSE

The purpose of this document is to establish the minimum requirements for the inspection of lift stations installed at the College of Nanoscale Science and Engineering and prevent leaks, spills and chemical reactions from occurring.

2 SCOPE

This External Appendix is limited to the lift stations owned by Semiconductor Manufacturing Technology (SEMATECH).

SEMATECH Annual Inspection Sheet

Building	Column Location	What it is connected to (Tool such as CNW02 or MAU #5)	Name of Inspector	Date Inspected	Visual Inspection Completed		Pump Cycled		Number of Cycles	Comments:
					Yes	No	Yes	No		
NFS	A.3.5	SBR03A Scrubber	B							
NFS	B5	WTS05a & Benign Exhaust Condensate	A							
NFS	C5	WTS04a Chem Drain	C							
NFS	E5	SBR1A Scrubber	B							
NFS	E5	WTS02a Chem Drain	B							
NFS	C5	CLN01a & City Water BFP WTS4a	A							
NFS	C5	City Water WTS4A	A							
NFS	C5	WTS04a Chem Drain	C							
NFS	D5	WTS03a Chem Drain	C							
NFS	D5	WTS03a BHF Drain: Drain pumped to HF Collection Unit	B							
NFS	E5	SBR1A Scrubber	B							
NFS	E5	CLN2A Chem Drain	A							
NFS	E5	SBR1A Scrubber	B							
NFS	E5	WTS02a Chem Drain	B							